Inspection Capabilities	Standard MRS Sensor	High-Speed MRS Sensor	High-Resolution MRS Sensor	Ultra-High Resolution MRS Sensor	
Inspection Speed	40 cm <sup>2</sup> /sec (2D+3D)	50 cm <sup>2</sup> /sec (2D+3D)	20 cm <sup>2</sup> /sec (2D+3D)	15 cm <sup>2</sup> /sec (2D+3D)	
XY Resolution	10 µm		7 μm		
Z Resolution	0.5 μm				
Minimum Feature Size	100 µm		70 μm		
Maximum Feature Size	SQ3000: 510 x 510 mm (20 x 20 in.), SQ3000-X: 710 x 610 mm (27.9 x 24 in.)				
Minimum Feature Height	50 µm				
Maximum Feature Height	24 mm		8 mm		
XY R&R	< 3 µm 1 sigma	< 3 µm 1 sigma		< 2 µm 1 sigma	
Z R&R	< 2 µm 1 sigma				
Accuracy XY	6μm		5 μm		
Accuracy Z	2 μm				
Height Clearance	Top: 50 mm ; Bottom: 30mm				
Carrier Thickness	0.3 - 5 mm (10 mm Option)				
	Line / Distance / X,Y / Mid Line, Inter Point / Regression Shifted, Datum X,Y / LSF X,Y Offset, X,Y Offset / Value / Location / List of X,Y Values, Height / Local Height / Regression / Radius, Coplanarity/ Distance to plane / 2nd Order fitting, Difference / Absolute / 2sqrt / VC, Max / Min / Ave / Sigma / Plus / Minus / Multiple				
	Coplanarity/ Distance Min / Ave / Sigma / P	e to plane / 2nd Order fi			
Vision System & Technology	Coplanarity/ Distance Min / Ave / Sigma / P	e to plane / 2nd Order fi			
Vision System & Technology Imagers	Coplanarity/ Distance Min / Ave / Sigma / P Multi-3D sensors	e to plane / 2nd Order fi	itting, Difference / Absc		
/ision System & Technology magers Resolution	Coplanarity/ Distance Min / Ave / Sigma / P Multi-3D sensors Sub 10 μm	e to plane / 2nd Order fi lus / Minus / Multiple	itting, Difference / Absc	olute / 2sqrt / VC, Max /	
/ision System & Technology magers Resolution Field of View (FOV)	Coplanarity/ Distance Min / Ave / Sigma / P Multi-3D sensors Sub 10 µm 36 x 30 mm	e to plane / 2nd Order fi lus / Minus / Multiple 36 x 36 mm	itting, Difference / Absc 7 μm 26 x 26 mm	olute / 2sqrt / VC, Max /	
Vision System & Technology Imagers Resolution Field of View (FOV) Image Processing	Coplanarity/ Distance Min / Ave / Sigma / P Multi-3D sensors Sub 10 µm 36 x 30 mm Autonomous Image I	e to plane / 2nd Order fi lus / Minus / Multiple 36 x 36 mm Interpretation (Al <sup>2</sup> ) Tech	itting, Difference / Absc	olute / 2sqrt / VC, Max /	
Vision System & Technology Imagers Resolution Field of View (FOV) Image Processing Programming Time	Coplanarity/ Distance Min / Ave / Sigma / P Multi-3D sensors Sub 10 µm 36 x 30 mm Autonomous Image I <13 minutes (for esta	e to plane / 2nd Order fi lus / Minus / Multiple 36 x 36 mm Interpretation (Al <sup>2</sup> ) Tech	itting, Difference / Absc 7 μm 26 x 26 mm	olute / 2sqrt / VC, Max / 21 x 21 mm d Lead Measurement	
Vision System & Technology magers Resolution Field of View (FOV) mage Processing Programming Time CAD Import	Coplanarity/ Distance Min / Ave / Sigma / P Multi-3D sensors Sub 10 µm 36 x 30 mm Autonomous Image I <13 minutes (for esta Any column-separate	e to plane / 2nd Order fi lus / Minus / Multiple 36 x 36 mm Interpretation (Al <sup>2</sup> ) Tech	itting, Difference / Absc 7 μm 26 x 26 mm mology, Coplanarity and	olute / 2sqrt / VC, Max / 21 x 21 mm d Lead Measurement	
Vision System & Technology magers Resolution Field of View (FOV) mage Processing Programming Time CAD Import System Specifications	Coplanarity/ Distance Min / Ave / Sigma / P Multi-3D sensors Sub 10 µm 36 x 30 mm Autonomous Image I <13 minutes (for esta Any column-separate	e to plane / 2nd Order fi lus / Minus / Multiple 36 x 36 mm Interpretation (Al <sup>2</sup> ) Tech Iblished libraries) ed text file with ref desig	itting, Difference / Absc 7 μm 26 x 26 mm mology, Coplanarity and	olute / 2sqrt / VC, Max / 21 x 21 mm d Lead Measurement	
Vision System & Technology Imagers Resolution Field of View (FOV) Image Processing Programming Time CAD Import System Specifications Machine Interface	Coplanarity/ Distance Min / Ave / Sigma / P Multi-3D sensors Sub 10 µm 36 x 30 mm Autonomous Image I <13 minutes (for esta Any column-separate preparation SMEMA, RS232 and E	e to plane / 2nd Order fi lus / Minus / Multiple 36 x 36 mm Interpretation (Al <sup>2</sup> ) Tech Iblished libraries) ed text file with ref desig	itting, Difference / Abso 7 μm 26 x 26 mm mology, Coplanarity and gnator, XY, Angle, Part n	olute / 2sqrt / VC, Max / 21 x 21 mm d Lead Measurement	
Vision System & Technology Imagers Resolution Field of View (FOV) Image Processing Programming Time CAD Import System Specifications Machine Interface Power Requirements Compressed Air	Coplanarity/ Distance Min / Ave / Sigma / P Multi-3D sensors Sub 10 µm 36 x 30 mm Autonomous Image I <13 minutes (for esta Any column-separate preparation SMEMA, RS232 and E 100-120 VAC or 220-2	e to plane / 2nd Order fi lus / Minus / Multiple 36 x 36 mm Interpretation (Al <sup>2</sup> ) Tech Iblished libraries) ed text file with ref design thernet	itting, Difference / Absc 7 μm 26 x 26 mm nology, Coplanarity and gnator, XY, Angle, Part n 5 amps	olute / 2sqrt / VC, Max / 21 x 21 mm d Lead Measurement	
Capability Vision System & Technology Imagers Resolution Field of View (FOV) Image Processing Programming Time CAD Import System Specifications Machine Interface Power Requirements Compressed Air Requirements System Dimensions	Coplanarity/ Distance Min / Ave / Sigma / P Multi-3D sensors Sub 10 µm 36 x 30 mm Autonomous Image I <13 minutes (for esta Any column-separate preparation SMEMA, RS232 and E 100-120 VAC or 220-2	e to plane / 2nd Order fi lus / Minus / Multiple 36 x 36 mm Interpretation (Al <sup>2</sup> ) Tech Iblished libraries) ed text file with ref desig thernet 240 VAC, 50/60 hz, 10-15 f/cm <sup>2</sup> (80 to 100 psi @ 4	itting, Difference / Absc 7 μm 26 x 26 mm nology, Coplanarity and gnator, XY, Angle, Part n 5 amps	olute / 2sqrt / VC, Max / 21 x 21 mm d Lead Measurement	
Vision System & Technology Imagers Resolution Field of View (FOV) Image Processing Programming Time CAD Import System Specifications Machine Interface Power Requirements Compressed Air Requirements	Coplanarity/ Distance Min / Ave / Sigma / P Multi-3D sensors Sub 10 µm 36 x 30 mm Autonomous Image I <13 minutes (for esta Any column-separate preparation SMEMA, RS232 and E 100-120 VAC or 220-2 5.6 Kgf/cm <sup>2</sup> to 7.0 Kg SQ3000: 110 x 127 x	e to plane / 2nd Order filus / Minus / Multiple 36 x 36 mm Interpretation (Al <sup>2</sup> ) Tech Iblished libraries) ed text file with ref design thernet 240 VAC, 50/60 hz, 10-15 f/cm <sup>2</sup> (80 to 100 psi @ 4 139 cm (W x D x H) x 139 cm (W x D x H) 27 lbs.)	itting, Difference / Absc 7 μm 26 x 26 mm nology, Coplanarity and gnator, XY, Angle, Part n 5 amps	olute / 2sqrt / VC, Max / 21 x 21 mm d Lead Measurement	

Barcode Reader, Rework station, SPC Software, Alignment Target

SQ3000<sup>™</sup> D (Dual Lane), and SQ3000<sup>™</sup> DD (Dual Lane - Dual Sensor) models available

## **OYBEROPTICS**

Contact CyberOptics today for more information +1 800.366.9131 or +1 763.542.5000 | CSsales@cyberoptics.com | www.cyberoptics.com

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# **SQ3000<sup>™</sup> 3D CMM**

The Ultimate in Speed and Accuracy for Semiconductor Applications

#### Fastest – Seconds, not Hours

- Reduces engineering resource time

#### **Easy-to-use Interface**

- Quick programming for complex applications
- Multi-process capable AOI, SPI, AOM, CMM

#### Metrology-grade Accuracy

Microelectronics and Metrology Applications







- Significantly speeds attaining coordinate measurements vs. traditional CMMs

Simplifies process with award-winning, intuitive, touch screen experience

Achieve metrology-grade accuracy with MRS-enabled technology Repeatable and reproducible measurements for SMT, Semiconductor,

# **OYBEROPTICS**

# SQ3000<sup>™</sup> The Ultimate in Speed and Accuracy

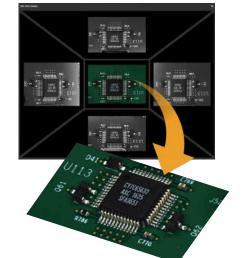
## High Precision Accuracy with Multi-Reflection Suppression<sup>™</sup> (MRS) Sensor Technology

The SQ3000 is powered by CyberOptics' breakthrough 3D sensing technology comprising four multi-view 3D sensors and a parallel projector delivering metrology grade accuracy at production speed. CyberOptics' unique sensor architecture simultaneously captures and transmits multiple images in parallel while proprietary 3D fusing algorithms merge the images together. The result is ultra-high quality 3D images and high-speed inspection.

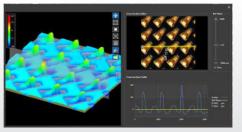
## **Multi-Reflection Suppression (MRS) Technology**

SQ3000 offers unmatched accuracy with the revolutionary MRS technology by meticulously identifying and rejecting reflections caused by shiny components. Effective suppression of multiple reflections is critical for accurate measurement making MRS an ideal technology solution for a wide range of applications including those with very high quality requirements.

CyberOptics has advanced the proprietary Multi-Reflection Suppression (MRS) sensor to an even finer resolution. The Ultra-High Resolution MRS sensor enhances the SQ3000 3D CMM platform, delivering superior inspection performance for socket metrology, advanced packaging, solder ball & bump, micro-electronics, and a variety of semiconductor applications where an even greater degree of accuracy and inspection reliability is critical.



**Solder Ball and Bump** 



**Socket Metrology** 



Packaging SMT

## **Large Board Capability**

SQ3000 X<sup>™</sup> supports large boards up to 710 x 610 mm, and is capable of inspecting the most demanding assemblies at production speed without compromising on measurement accuracy and repeatability.



### Intuitive, Easy-to-Use Software

The multi-award winning SQ3000 AOI software is a more powerful yet extremely simple software designed with an intuitive interface. Including multi-touch controls, 3D image visualization tools and ultra-fast programming capabilities that brings ease-of-use to a completely new level, which reduces training efforts and minimizes operator interaction - saving time and cost.

## **Enable Smarter, Faster Inspection**

Reduce time to program and tune with ultra-fast programming capabilities including auto tuning and enhancements that significantly speed setup, simplify the process, reduce training efforts and minimize operator interaction. Al<sup>2</sup> (Autonomous Image Interpretation) technology is all about keeping it simple - no parameters to adjust or algorithms to tune. And, you don't need to anticipate defects or pre-define variance either - Al<sup>2</sup> does it all for you. With Al<sup>2</sup>, you have the power to inspect the most comprehensive list of features and identify the widest variety of defects. Al<sup>2</sup> offers precise discrimination with just one panel inspection making it a perfect solution for high-mix and high-volume applications.

## Seconds, not Hours - Faster, Highly Accurate Coordinate Measurement Suite (CMM)

CyberCMM<sup>™</sup>, a comprehensive software suite of coordinate measurement tools provides highly accurate, 100% metrology-grade measurement on all critical points much faster than a traditional CMM, including coplanarity, distance, height and datum X, Y to name a few. A fast and easy set-up can be performed in less than an hour for programming complex applications as compared to slow, engineering resource-intensive set-up that typically requires multiple adjustments with traditional coordinate measurement machines (CMMs)

### Fast, Scalable SPC Solution

CyberReport<sup>™</sup> offers full-fledged machine-level to factory-level SPC capability with powerful historical analysis and reporting tools delivering complete traceability for process verification and yield improvement. CyberReport<sup>™</sup> is easy to setup and simple to use while providing fast charting with a compact database size.

